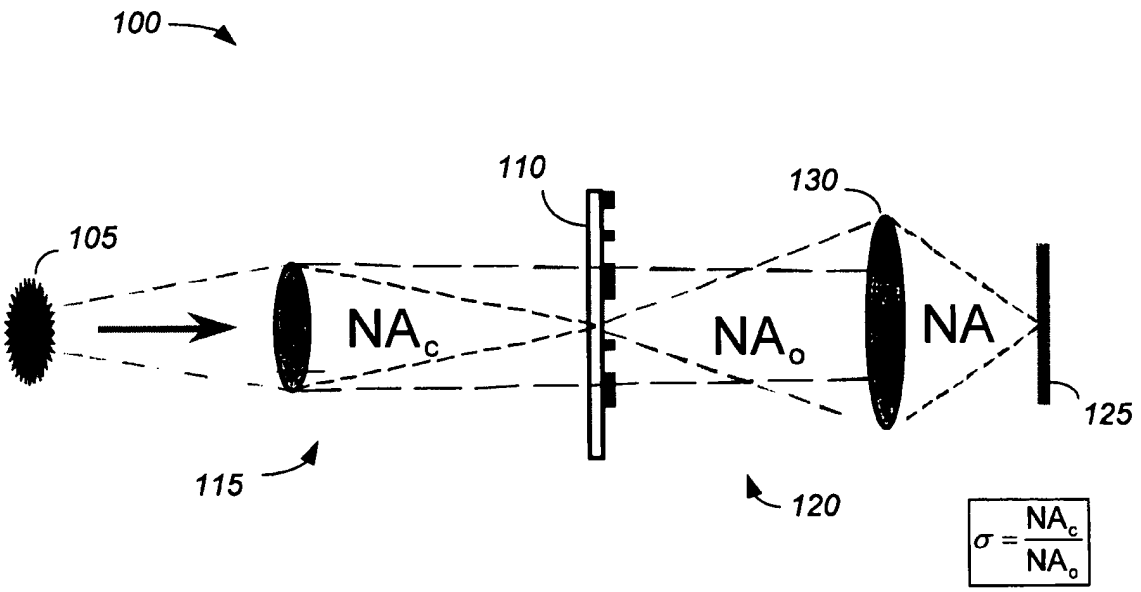

FIG. 1

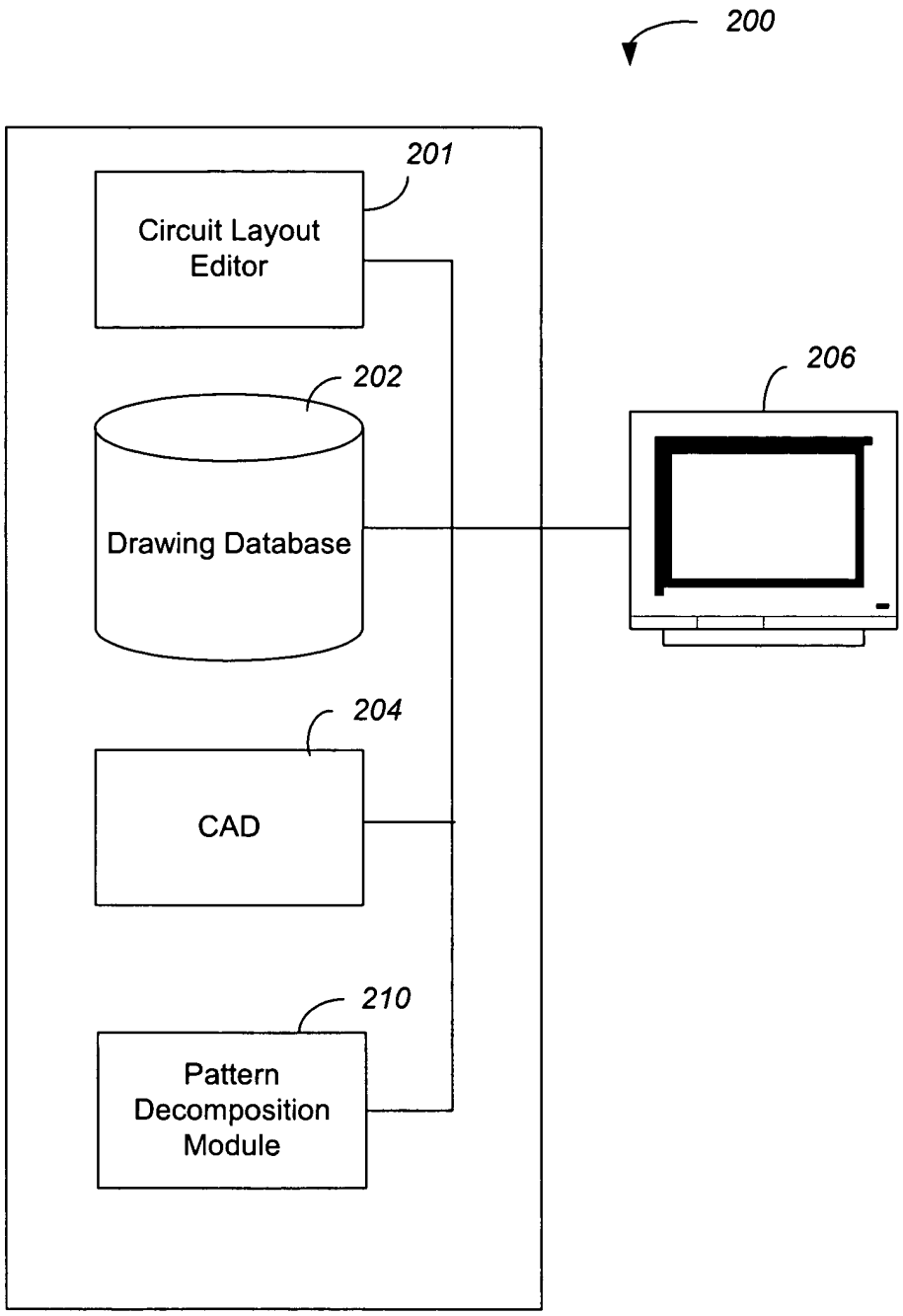
200
201
Circuit Layout Editor
202
Drawing Database
206
204
CAD
210
Pattern Decomposition Module

FIG. 2

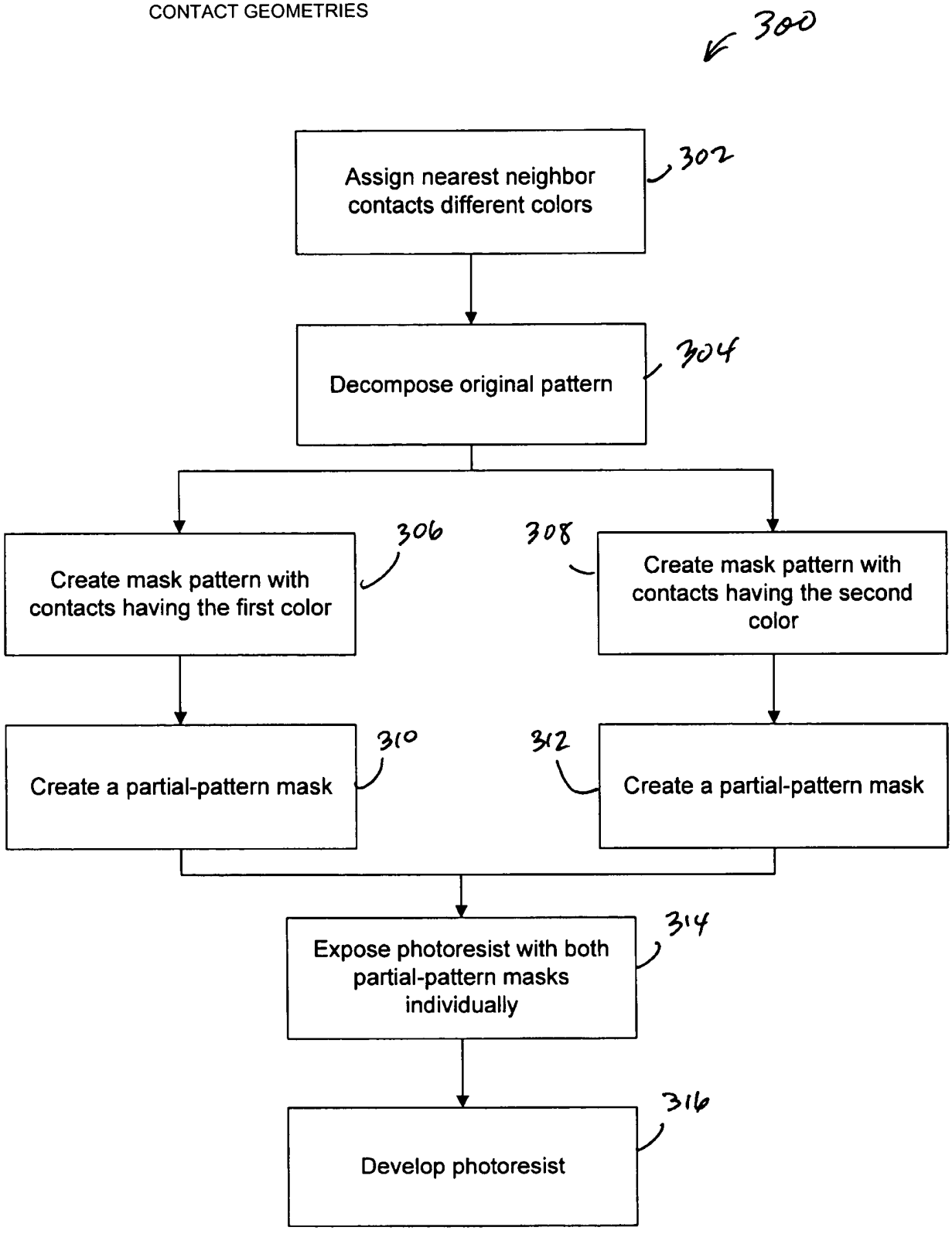
300
Assign nearest neighbor contacts different colors
302
Decompose original pattern
304
Create mask pattern with contacts having the first color
306
Create mask pattern with contacts having the second color
308
Create a partial-pattern mask
310
Create a partial-pattern mask
312
Expose photoresist with both partial-pattern masks individually
314
Develop photoresist
316

FIG. 3

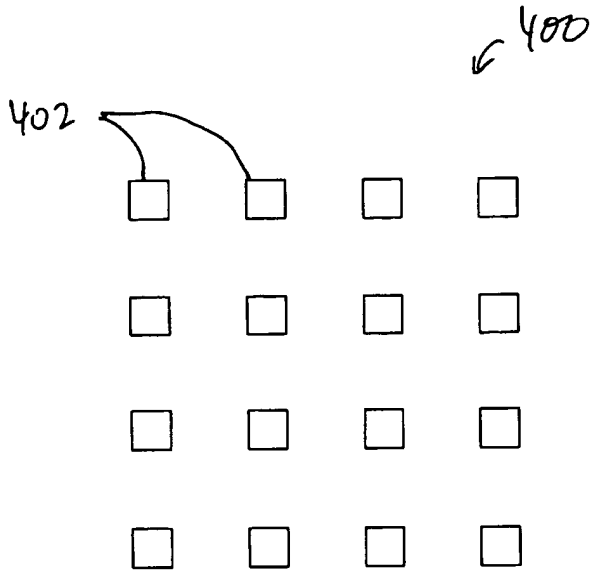

FIG. 4

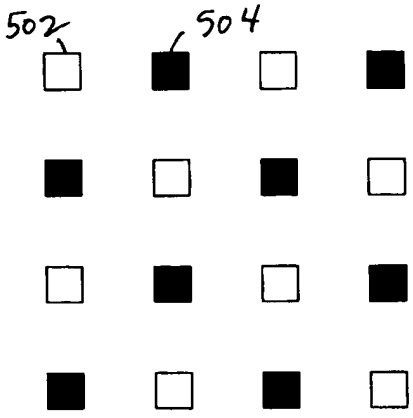

FIG. 5

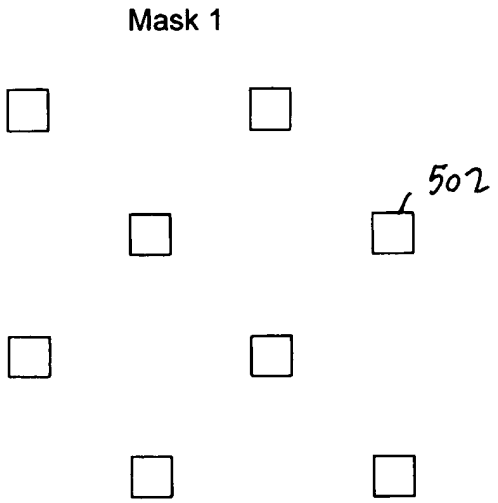

FIG. 6A

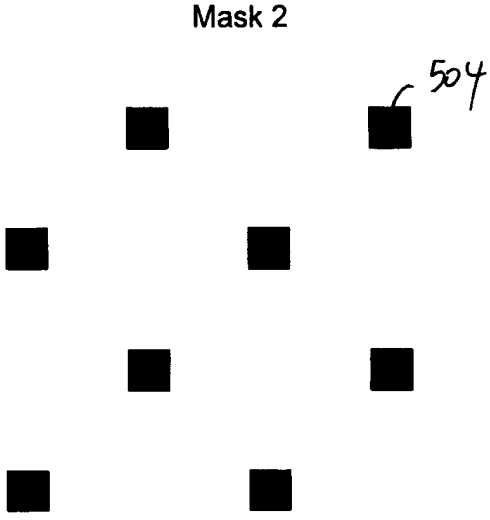

FIG. 6B